

AF/2828
IFW #

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q54431

Toshiro HAYAKAWA, et al.

Appln. No.: 09/315,068

Group Art Unit: 2828

Confirmation No.: 5982

Examiner: Dung T. NGUYEN

Filed: May 20, 1999

For: SEMICONDUCTOR LASER AND METHOD OF MANUFACTURING THE SAME

NOTICE OF APPEAL

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


Sir:

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the final Office Action dated February 11, 2004.

The statutory fee of \$330.00 is to be charged to Deposit Account No. 19-4880. The USPTO is directed and authorized to charge all required fees, except for the Issue Fee and the Publication Fee, to Deposit Account No. 19-4880. Please also credit any overpayments to said Deposit Account. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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WASHINGTON OFFICE

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CUSTOMER NUMBER

Date: August 11, 2004

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